Listing of Claims:

Claims 1-30 (Cancelled)

31. (Original) A sequential resonant tunneling device for back-side illumination, comprising an alternating semiconductor layer structure as follows:

	Material		Thickness	Dopant	Doping level
			(nm)		
	c-plane	(0001)	Not limited	Not limited	Not limited
	sapphire subst	rate			
	AlN		10	un-doped	0
	$Al_{0.2}Ga_{0.8}N$ $Al_{0.27}Ga_{0.73}N$		1000	silicon	1x1018 cm-3
	$Al_{0.27}Ga_{0.73}N$		5	undoped	0
	GaN		4	undoped	0
QW unit	$\begin{cases} Al_{0.27}Ga_{0.73}N \\ GaN \end{cases}$		7	undoped	0
	€ GaN		4	undoped	0
30 QW units			į		į
	$Al_{0.27}Ga_{0.73}N$		7	undoped	0
	GaN		4	undoped	0
	$Al_{0.27}Ga_{0.73}N$		5	undoped	0
	GaN		300	magnesium	1x1018 cm-3

32. (Original) The sequential resonant tunneling device according to claim 31, further comprising metal contacts on surfaces of n and p type semiconductors.

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33. (Original) A sequential resonant tunneling device for front-side illumination, comprising a multi-layered semiconductor structure, as follows:

	Material		Thickness	Dopant	Doping level
			(nm)		
	c-plane	(0001)	Not limited	Not limited	Not limited
	sapphire substr	rate			
	AlN		10	Undoped	0
	GaN		1000	Silicon	1x1018 cm-3
	$Al_{0.25}Ga_{0.75}N$		5	Undoped	0
	GaN		4	Undoped	0
QW unit A	$\int Al_{0.25}Ga_{0.75}N$		7	Undoped	0
	€ GaN		4	Undoped	0
30 periods				į	
QW unit A	$Al_{0.27}Ga_{0.73}N$		7	Undoped	0
	GaN		4	Undoped	0
QW unit B	$\begin{cases} Al_{0.25}Ga_{0.75}N \\ Al_{0.33}Ga_{0.67}N \end{cases}$		4	magnesium	1x1018 cm-3
	$\bigcup Al_{0.33}Ga_{0.67}N$		4	magnesium	1x1018 cm-3
25 periods QW unit B		·	•	į	į
	$ \begin{array}{c} Al_{0.25}Ga_{0.75}N \\ Al_{0.33}Ga_{0.67}N \end{array} $		4	magnesium	1x1018 cm-3
	$\left(\begin{array}{c} Al_{0.33}Ga_{0.67}N \end{array}\right.$		4	magnesium	1x1018 cm-3
	GaN		10	magnesium	1x1018 cm-3

34. (Original) The sequential resonant tunneling device according to claim 33, further comprising metal contacts on surfaces of n and p type semiconductors.

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35. (Original) A sequential resonant tunneling device for front-side illumination comprising a multilayered semiconductor structure as follows:

	Material	Thickness	Dopant	Doping level
		(nm)	,	
	6H-SiC substrate	Not limited	p-type	1x1018 cm-3
	AlN	10	un-doped	0
	$\mathrm{Al}_{0.27}\mathrm{Ga}_{0.73}\mathrm{N}$	5	Undoped	0
QW unit	GaN	4	Undoped	0
	$\begin{cases} Al_{0.27}Ga_{0.73}N \\ GaN \end{cases}$	7	Undoped	0
	∫ GaN	4	Undoped	0
30 periods QW units				
	$\overline{Al_{0.27}Ga_{0.73}N}$	7	Undoped	0
	GaN	4	Undoped	0
	$\mathrm{Al}_{0.27}\mathrm{Ga}_{0.73}\mathrm{N}$	5	Undoped	0
	Al _{0.27} Ga _{0.73} N Al _{0.2} Ga _{0.8} N	1000	Silicon	1x1018 cm-3
	GaN	10	Silicon	1x1018 cm-3

36. (Original) The sequential resonant tunneling device according to claim 35, further comprising metal contacts on surfaces of n and p type semiconductors.

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37. (Cancelled)

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